

FORM PTO-1449 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(37 CFR 1.98(b))

OCT 19 2001

Attorney Docket No.: W&B-INF-701
Appl. No. 09/917,549

Applicant Harald Richter et al.

Filing Date July 27, 2001

Group Art Unit 1763

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
<i>AWO</i>	A	5,910,453	6/8/99	Gupta et al.	437	717	
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						

FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
<i>AWO</i>	J	11 150 115 A	6/2/99	Japan			
	K						
	L						
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

<i>AWO</i>		Tanabe: "Reactive Ion Etching of AL Alloy Films in a Rotating Magnetic Field", Jpn. J. Appl. Phys., Vol. 32, Part 1, No. 2, dated February 1993, pp. 747-752;

EXAMINER

Alta Ober

DATE CONSIDERED

9/13/02

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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TC 1700